Title (en)

A SECONDARY ELECTRON SPECTROMETER FOR MAKING MEASUREMENTS OF THE POTENTIAL ON A SAMPLE WITH AN ELECTRON PROBE

Publication

EP 0075709 A3 19830629 (DE)

Application

EP 82107490 A 19820817

Priority

DE 3138929 A 19810930

Abstract (en)

[origin: US4514682A] An improved secondary electron spectrometer for measuring voltages occurring on a specimen, such as an integrated circuit chip, utilizing an electron probe has a grating structure for measuring the energy distribution of the secondary electrons independently of the angular distribution of the secondary electrons at the measuring point on the specimen. If the secondary electron spectrometer has an extraction electrode and a deceleration electrode, the grating structure is spherically symmetric.

IPC 1-7

H01J 49/44; H01J 49/08; G01R 31/28

IPC 8 full level

G01R 31/26 (2006.01); **G01Q 30/02** (2010.01); **G01R 31/28** (2006.01); **G01R 31/302** (2006.01); **H01J 37/252** (2006.01); **H01J 49/08** (2006.01); **H01J 49/44** (2006.01); **H01L 21/66** (2006.01)

CPC (source: EP US)

H01J 49/08 (2013.01 - EP US); **H01J 49/44** (2013.01 - EP US)

Citation (search report)

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- US 3764898 A 19731009 - BOHLEN H, et al
- "TECHNISCHES MESSEN TM", 48 Jahrgang 1981, Heft 1, R. Oldenbourg Verlag GmbH, München. P. FAZEKAS: "Elektronenstrahl pruft elektrische Potentiale in integrierten Schaltungen", Seiten 29-35

Cited by

EP0268232A3

Designated contracting state (EPC)

DE FR GB NL

DOCDB simple family (publication)

EP 0075709 A2 19830406; **EP 0075709 A3 19830629**; **EP 0075709 B1 19870408**; DE 3138929 A1 19830414; DE 3276035 D1 19870514; JP S5871542 A 19830428; JP S6352428 B2 19881019; US 4514682 A 19850430

DOCDB simple family (application)

EP 82107490 A 19820817; DE 3138929 A 19810930; DE 3276035 T 19820817; JP 16823982 A 19820927; US 39854282 A 19820715